ICATION

| OIP | 15089-2 | | PATENT APPL |
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| JUL 2 | IN THE UNITED STATES PA | TENT A | AND TRADEMARK OFFICE |
| ELECT. | In re Application of: |) | Errorring on ASSAE EAVEZ C |
| GAL | GLENN CLARKE ET AL. | ; | Examiner: ASSAF, FAYEZ G. |
| | Application No.: 10/840,134 | : | TC/Art Unit: 2872 |
| | Filed: 05/06/2004 | : | |
| | For: METHOD OF MAKING HIGHLY | : | |
| | DISCRIMINATING OPTICAL EDGE | : | X 1 01 0005 |
| | FILTERS AND RESULTING PRODUCTS | 1 | Inly 21 2005 |

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 form. A copy of each listed document is enclosed, except for U.S. patents and published U.S. patent applications.

> I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

July 21, 2005 **Date of Transmission** Daniel D. Sierchio (Reg. No. 53,591) **Printed Name**

Date of Signature

Signature

Applicants' undersigned attorney may be reached by telephone at (973) 597-2500.

All correspondence should continue to be directed to our address listed below.

Respectfully submitted,

Daniel D. Sierchio

Attorney for Applicants

Registration No. __53,591

DOCKET ADMINISTRATOR Lowenstein Sandler PC 65 Livingston Avenue Roseland, NJ 07068

Application Number Docket Number (Optional) JUL 2 5 2005 10/840,134 15789-2 INFORMATION DISCLOSURE CITATION (Use several sheets if necessary) Applicant(s) **GLENN CLARKE ET AL.** Filing Date **Group Art Unit** 05/06/2004 2872 **U.S. PATENT DOCUMENTS** FILING DATE IF APPROPRIATE EXAMINER INITIAL SUBCLASS REF DOCUMENT NUMBER DATE NAME CLASS 05/26/05 417 2005/0110999 Erdogan et al. 356

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Examiner Signature

Date Considered

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO-A820 (also form PTO-1449)

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

| _ | Docket Number (Optional) 15789-2 | Application Number 10/840,134 | | | |
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| | Applicant(s) Glenn Clarke et al. | | | | |
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